



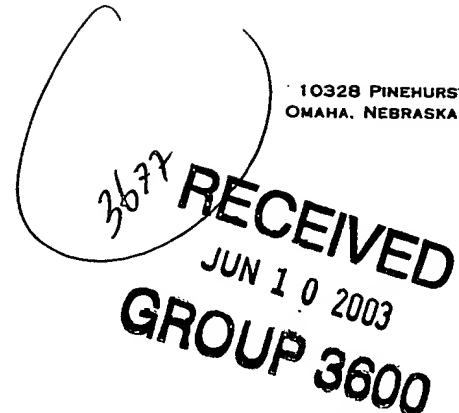
JAMES D. WELCH
ATTORNEY AT LAW
PROFESSIONAL ENGINEER

publishing
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10328 PINEHURST AVE.
OMAHA, NEBRASKA 68124

May 21, 2003



Commissioner for Patents
P.O. BOX 1450
Alexandria, VA 22313-1450

RE: OPPOSITION BY THIRD PARTY REGARDING PUBLISHED APPLICATION OF
ZAIDI ET AL. ET AL. TITLED: "OPTICAL MEASUREMENT OF
PLANARIZED FEATURES";
PUB. NO. US2003/0063272 A1;
PUB. DATE: APR. 3, 2003;
SERIAL NO. 09/996,506

OPPOSITION TO PUBLISHED U.S. PATENT APPLICATION

Dear Sir;

Enclosed please find a check for \$180.00 to cover the cost of submittal, and a Listing of Printed Materials submitted under 37 C.F.R. 1.99.

PATENT NO. 5,936,734 TO JOHS ET AL. FILED 12/23/97, ISSUED AUG. 10, 1999.

PATENT NO 5,739,909 TO BLAYO ET AL., FILED 10/10/95, ISSUED APR. 14, 1998.

PATENT NO. 5,900,633 TO SOLOMON ET AL. FILED 12/15/97, ISSUED MAY 4, 1999.

PATENT NO. 6,552,812 TO XU ET AL., FILED AUG 10, 2000, ISSUED APR. 22, 2003.

PATENT NO. 6,321,601 TO MARIS FILED 09/23/99, ISSUED NOV. 27, 2002.

ARTICLE TITLED "REAL-TIME ULTRAVIOLET ELLIPSOMETRY MONITORING OF GATE PATTERNING IN A HIGH-DENSITY PLASMA", VALLON ET AL., J. VAC. SCI. TECHNOL. A 15(3), (MAY/JUN 1997).

ARTICLE TITLED "MULTIWAVELENGTH ELLIPSOMETRY FOR REAL-TIME PROCESS CONTROL OF THE PLASMA ETCHING OF PATTERNED SAMPLES", MAYNARD ET AL., J. VAC. SCI. TECHNOL. B 15(1), (JAN/FEB 1997).

05/27/2003 MMHAMMI 00000018 10996506

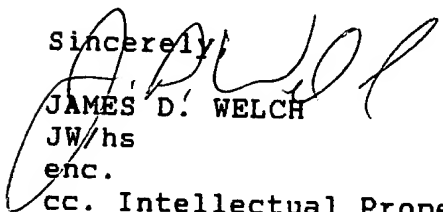
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180.00 OP

ARTICLE TITLED "ULTRAVIOLET-VISIBLE ELLIPSOMETRY FOR PROCESS CONTROL DURING THE ETCHING OF SUBMICROMETER FEATURES", BLAYO ET AL., J. OPT. SOC. AM. VOL. 12, NO. 3, (MARCH 1995).

I hereby attest that Service was made on the Applicant's Attorney at Infineon Technologies North America Group, c/o Siemens Corp., Intellectual Property Department, 186 Wood Avenue South Iselin, NJ 08830 via First Class mail sent May 21, 2003.

Sincerely,



JAMES D. WELCH

JW/hs

enc.

cc. Intellectual Property Group, Infineon Technologies North America Group, c/o Siemens Corp.